

IN THE SPECIFICATION

Please amend the paragraph beginning at page 1, starting at line 5 (first paragraph), as follows:

This application is a continuation-in-part of serial no. 09/801,566, filed 03/07/2001 (now U.S. Patent No. 6,640,027 B2), which is a continuation-in-part of serial no. 09/765,971 filed 01/19/2001 (now U.S. Patent No. 6,631,224 B2), which is a continuation-in-part of serial no. 09/729,661 filed 12/04/2000 (now U.S. Patent No. 6,510,261 B2), which is a continuation-in-part of serial no. 09/666,763 filed 09/21/2000 (now U.S. Patent No. 6,539,148 B1), which application is a continuation-in-part of and claims the benefit of priority from Provisional Patent Application Serial No. 60/206,767, filed 05/23/2000, serial no. 09/666,763 also being a continuation in part of serial no. 09/571,092 filed 05/15/2000 (now U.S. Patent No. 6,253,002), which is a continuation of serial no. 09/425,099 filed 09/23/1999 (now U.S. Patent No. 6,233,379), which is a continuation-in-part of serial no. 09/022,413 filed 02/12/1998 (now U.S. Patent No. 6,021,237), which claims priority to KR 97-24796 filed 06/06/1997 (now Korean Patent No. 10-0265865, registered June 17, 2000), all of which applications are fully incorporated herein by reference.

Please amend the paragraph beginning at page 47, starting at line 13 (second paragraph), as follows:

Figure 44 illustrates an embodiment where perturbing structure 512 includes a plurality of piezo-translators 516 and spacers 518 that produce transverse displacements of optical waveguide 514. Optical waveguide 514 is attached to the top of each piezo-translator 516 so that height changes in piezo-translators 516 produce a

bending of optical waveguide 514. Piezo-translators 516 and spacers 518 are attached to a rigid substrate 519 that does not bend). Substrat Substrate 519 and spacers 518 are optional. Alternatively,, a backing can be used to maintain contact between optical waveguide 514 and piezo_translators 516. The backing_518 is flexible enough to not inhibit optical waveguide 514 from bending. Piezo-translators 516 can be either plates operating in the d13 direction,- in the d33 direction, or shear-mode piezo-transducers can be utilized that operate in the d15 direction.